Product Reliability Qualification Strategy & Report PPAP Quad source TJA1028TK/5V0/10, TJA1028TK/5V0/20, TJA1042TK/3, TJA1049TK, TJA1049TK/3, TJA1051TK/3

3.0 — August 25, 2022

Document information

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1.0	September 9, 2020	Initial revision.	Tino Heijmen
2.0	October 20, 2021	Results added for TJA1042TK/3	Tino Heijmen
3.0	August 25, 2022	Results added for TJA1051TK/3	Tino Heijmen

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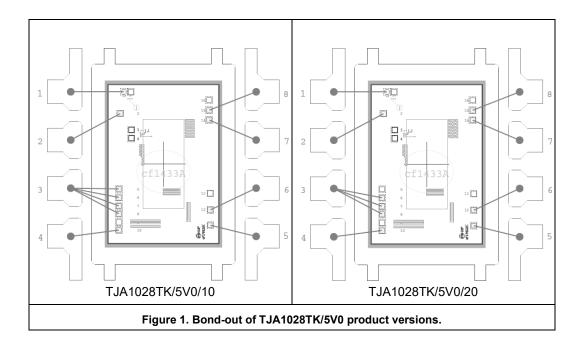
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1. Summary

The current report describes the failure-mechanism based stress-test qualification of second-source assembly release of the product types listed in Table 1. All products in scope are assembled in HVSON8 (SOT782-1) and are assembly second-sourced from ATBK to ASEN¹. In addition, the released product types are front-end dual-sourced in wafer-fabrication process (A-BCD3) from ICN8 to SSMC. Section 3.12 describes the wire-diameter change from 20 to 18 μm in ATBK for TJA1028TK/5V0/XX (XX = 10 or 20), TJA1042TK/3, and TJA1051TK/3 manufactured either in ICN8 or SSMC. The extensions "/10" and "/20" in the TJA1028 product name are related to the supported baud rate, see the product datasheet. The difference between the "low-slope" TJA1028TK/5V0/10 and the "normal-slope" TJA1028TK/5V0/ is determined by the wire bond-out, see Figure 1.

Table 1. Product types qualified with the results reported in the current report.

Type name	Grade	Ambient Operating Temperature Range
TJA1028TK/5V0/XX ²	1	-40 °C to +125 °C
TJA1042TK/3	1	-40 °C to +125 °C
TJA1049TK	1	-40 °C to +125 °C
TJA1049TK/3	1	-40 °C to +125 °C
TJA1051TK/3	1	-40 °C to +125 °C



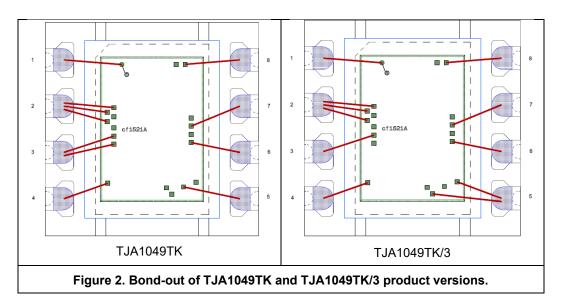
The difference between TJA1049TK and TJA1049TK/3 is also determined by the wire bond-out, see Figure 2.

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¹ Currently, ASEN is named ATX-SZ.

 $^{^{2}}$ XX = 10 or 20.



The qualification strategy has been defined according to NXP's internal reliability qualification policy and customer requirements. The strategy has been compliant with the automotive standard AEC Q100 Revision G.

Where possible, generic data have been used to satisfy qualification requirements. Test samples have been representative of the applied wafer-fab and assembly processes. All qualification devices were produced on tooling and processes at the manufacturing sites that are used to support part deliveries at production volumes.

The qualification program document in the current report has been completed successfully. As a result, the product types have been AEC Q100 qualified and released.

2. Qualification test results

2.1 Qualification material

For reliability qualification testing of TJA1028TK, the "normal-slope" version TJA1028TK/5V0/20 was used. "Low-slope" version TJA1028TK/5V0/10 is structural similar to the normal-slope version for all reported tests.

Table 2. Qualification lots.

abio zi dadii									
			New stre	ess test results – ge	enerated on the pro	oduct type(s) to be	qualified		
Qual lot ID	Lot 1	Lot 2	Lot 3	Lot 4	Lot 5	Lot 6	Lot 7	Lot 8	Lot 9
Product name	TJA1028TK	TJA1028TK	TJA1028TK	TJA1049TK/3	TJA1028TK	TJA1028TK	TJA1049TK/3	TJA1028TK	TJA1028TK
Design version	tf1433A	tf1433A	tf1433A	tf1521A	cf1433A	cf1433A	tcf1521A	tf1433A	cf1433A
Package	SOT782-1	SOT782-1	SOT782-1	SOT782-1	SOT782-1	SOT782-1	SOT782-1	SOT782-1	SOT782-1
Wafer fab site	SSMC	SSMC	SSMC	SSMC	ICN8	ICN8	ICN8	SSMC	ICN8
Wafer batch ID	SNW093.1	N/A	SNW093.1	SKG962.1	CHX810	CWT758	CWW4632	SNW093.104	CWT758
Wafer slice nr	6	N/A	8	15	1	2	22	4	6
Assembly site	ASEN	ASEN	ASEN	ASEN	ASEN	ASEN	ASEN	ATBK	ATBK
Assy date code	N0S939694000	N/A	N0S944EWT200	N0S944EVW200	N0S945418100	N0S939697000	N0S944EU6100	N0S931CAN100	N0S930DKC110
Used for test(s)	MSLA/HAST/ TC/HTSL/ CDM/ConAna MSLA/HAST/ BL-TC HAST/TC/ HTSL			CDM / ConAna	MSLA/HAST/ TC/HTSL/ ConAna	CDM	CDM / ConAna	CDM / ConAna	CDM / ConAna

			New st	tress test results – g	enerated on the pro	duct type(s) to be qu	ualified		
Qual lot ID	Lot 1	Lot 2	Lot 3	Lot 4	Lot 5	Lot 6	Lot 7	Lot 8	Lot 9
Product name	TJA1028TK	TJA1028TK	TJA1028TK	TJA1049TK/3	TJA1028TK	TJA1028TK	TJA1049TK/3	TJA1028TK	TJA1028TK
Design version	tf1433A	tf1433A	tf1433A	tf1521A	cf1433A	cf1433A	tcf1521A	tf1433A	cf1433A
Package	SOT782-1	SOT782-1	SOT782-1	SOT782-1	SOT782-1	SOT782-1	SOT782-1	SOT782-1	SOT782-1
Wafer fab site	SSMC	SSMC	SSMC	SSMC	ICN8	ICN8	ICN8	SSMC	ICN8
Wafer batch ID	SNW093.1	N/A	SNW093.1	SKG962.1	CHX810	CWT758	CWW4632	SNW093.104	CWT758
Wafer slice nr	6	N/A	8	15	1	2	22	4	6
Assembly site	ASEN	ASEN	ASEN	ASEN	ASEN	ASEN	ASEN	ATBK	ATBK
Assy date code	N0S939694000	N/A	N0S944EWT200	N0S944EVW200	N0S945418100	N0S939697000	N0S944EU6100	N0S931CAN100	N0S930DKC110
Used for test(s)	MSLA / HAST / TC / HTSL / CDM BL-TC HAST / / ConAna BL-TC		HAST/TC/HTSL	CDM / ConAna	MSLA/HAST/ TC/HTSL/ ConAna	CDM	CDM / ConAna	CDM / ConAna	CDM / ConAna

			Generic data -	- previously genera	ted on the current p	product type(s)				
Qual lot ID	Lot 18	Lot 19	Lot 20	Lot 21	Lot 22	Lot 23	Lot 23 Lot 24			
Product name	TJA1028	TJA1028	TJA1028	TJA1049	TJA1028	TJA1028	TJA1028TK	TJA1028TK		
Package	S08	S08	S08	S08	S08	S08	HSVON8	HSVON8		
Wafer fab site	ICN8	ICN8	ICN8	ICN8	ICN8	SSMC	ICN8	SSMC		
Wafer batch ID	CS4074	CS4580	CS5276	CR9492	CS4580	S98789.1	CT0240	S98789.1		
Wafer slice nr				02	01, 02					
Assembly site	ATBK	ATBK	ATBK	ATBK	ATBK	ATBK	ATBK	ATBK		
Used for test(s)	HTOL	HTOL	HTOL	HTOL	НВМ	НВМ	CDM	MSLA/HAST/ TC/HTSL/ CDM/ConAna		

			Generic data -	- previously genera	ted on the current p	product type(s)		
Qual lot ID	Lot 26	Lot 27	Lot 28	Lot 29	Lot 30	Lot 31	Lot 32	Lot 33
Product name	TJA1049	TJA1049	TJA1049/3	TJA1049/3	TJA1049TK	TJA1049TK	TJA1049TK/3	TJA1049TK/3
Package	S08	S08	S08	S08	HVSON8	HVSON8	HVSON8	HVSON8
Wafer fab site	ICN8	SSMC	ICN8	SSMC	ICN8	SSMC	ICN8	SSMC
Wafer batch ID	CKX813	S64678.1	CW5734	S64678.1	CKX813	S64678.1	CW5734	S64678.1
Wafer slice nr								
Assembly site	ATBK ATBI		ATBK	ATBK	ATBK	ATBK	ATBK	ATBK
Used for test(s)	est(s) HBM HBM		НВМ	НВМ	CDM	MSLA / HAST / TC / HTSL / CDM / ConAna	CDM	CDM

					Generic da	ıta – previously ger	nerated on other pro	oduct types							
Qual lot ID	Lot 34	Lot 34	Lot 35	Lot 36	Lot 37	Lot 38	Lot 39	Lot 40	Lot 41	Lot 42	Lot 43	Lot 44			
Product name	N/A	TJA1042	TJA1044	UJA1078	UJA1078	TJA1051	UJA1078A	UJA1078A	UJA1078A	TJA1059TK	TJA1059TK	TJA1059TK			
Design version															
Package	HVSON8	HVSON8 S08 S08 HTSSOP32 HTSSOP32 S08 HTSSOP32 HTSSOP32 HTSSOP32 HTSSOP32 HTSSOP34 HVSON14 HVSON14 HVSON14 HVSON14													
Wafer fab site	N/A	ICN8	ICN8	ICN8	ICN8	ICN8	SSMC	SSMC	SSMC	ICN8	ICN8	ICN8			
Wafer batch ID	N/A	CK0984	CAY862	CR1469	CR1748	CM3461	S98633	S98787	S98728	CYS434	CYS431	CYS323			
Wafer slice nr	N/A	02	08	05	01,03	05	2	1	2						
Assembly site	ATBK	ATBK	ATBK	ATBK	ATBK	ATBK	ATBK	ATBK	ATBK	ATBK	ATBK	ATBK			
Assy date code										2034	2035	2036			
Used for test(s)	DIMS	HTOL	HTOL	ELFR	ELFR	ELFR	HTOL, ELFR	HTOL, ELFR	HTOL, ELFR	UHAST	UHAST	UHAST			

2.2 Stress test results

Table 3. Test group A – Accelerated environmental stress tests.

						New stress the produ	test results – ç ct type(s) to be	generated on e qualified	Generic data – previously generated on the current product type(s)		ı – previously ner product typ		
Q100 Test#	Test abbr.	Stress test conditions	Read-points	ATE temperatures	Required total # units	Lot 1	Lot 3	Lot 5	Lot 25	Lot 42	Lot 43	Lot 44	Comments
	MSLA	Moisture Sensitivity Level Assessment / Verification			1 x 14	MSL L1		MSL L1	MSL L1				
			0 Hrs.			0/77	0/77	0/77	0/77				
			PCON			0 / 77	0 / 77	0/77	0/77				
		Highly Accelerated	96 hrs	R, H	3 x 77	0/77	0/77	0/77	0/77				
A1 + A2	PCON L.1 + HAST	Stress Test @ 130 °C / 85% RH	192 hrs			0/77	0/77	0/77	0/77				
	1,5101	Vstress = 28 V	384 hrs			0 / 77							
			CSAM 0 hrs		3 x 14	0 / 14	0 / 14	2 / 14 ^a					
			CSAM PCON		3 X 14	0 / 14	0 / 14	0 / 14					
			0 Hrs.							0/77	0/77	0/77	
	PCON L1 + A	Unbiased Highly	PCON		3 x 77					0/77	0/77	0/77	
A1 + A3		Test	96 hrs	R						0/77	0/77	0/77	UHAST is also covered by HAST.
	O I I A O I	@ 130 °C / 85% RH	192 hrs										
		1	384 hrs										
			0 Hrs.			0/77	0/77	0/77	0/77				
			PCON			0/77	0/77	0/77	0/77				
			500 cycles	R, H	3 x 77	0/77	0/77	0/77	0/77				
	PCON L.1 +	Temperature Cycling @ -65 to +150 °C	1000 cycles			0/77	0/77	0/77	0/77				
A1 + A4	TC	with WBP (#C2) after	1500 cycles			0/77			0/77				
		TC	CSAM 0 hrs			0 / 14	0 / 14	0/14	0/14				
			CSAM PCON		3 x 14	0 / 14	0 / 14	0/14	0 / 14				
			WBP 500 cycles		3 x 5	0/5	0/5	0/5	0/5				
			0 Hrs										
			CSAM										
4.5		Power Temperature	PCON	5	4 45								PTC is not required as maximum rated power < 1
A 5	PTC	Cycling @ -40 to +125 °C	CSAM	R, H	1 x 45								Watt and delta Tj < 40 °C.
		.20 0	1000 cycles										
			2000 cycles										
		III-b T	0 Hrs			0/77	0/77	0/77	0/77				
A 6	HTSL	High Temperature Storage Life	500 hrs	R, H	3 x 77	0/77	0/77	0/77	0/77				
		@ 175 °C	1000 hrs			0/77	0/77	0/77	0/77				

Notes:

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a Lead delamination was observed after pre-conditioning. This problem has been addressed and resolved, see section 2.3.2.

Table 4. Test group B – Accelerated lifetime simulation tests.

						Gene	eric data – pre	viously genera	ated on the cur	rent product ty	pe(s)	G	Seneric data –	previously ger	nerated on other	er product type	es	
Q100 Test#	Test abbr.	Stress test conditions	Read-points	ATE temperature	Required total # units	Lot 18	Lot 19	Lot 20	Lot 21	Lot 34	Lot 35	Lot 36	Lot 37	Lot 38	Lot 39	Lot 40	Lot 41	Comments
			0 Hrs.			0/77	0/77	0/77	0/77	0/77	0/77				0/77	0/77	0/77	
		High Temperature	168 Hrs			0/77	0/77	0/77	0/77	0/77	0/77				0/77	0/77	0/77	
B1	HTOL	Operating Life	1008 Hrs	R, C, H	3 x 77	0/77	0/77	0/77	0/77	0/77	0/77				0/77	0/77	0/77	
		(Intrinsic Life) @ Tj ≥ 150 °C	2016 Hrs	1, 0, 11	J XIII	0/77				0/77	0/77				0/77	0/77		
		Grade 1	3024 Hrs							0/77	0/77				0/77			
			4032 Hrs							0/77	0/77				0/77			
B2	FLED	Early Life Failure Rate	0 Hrs.	R, H	3 x 800							0 / 800	0 / 800	0 / 800	0 / 800	0 / 800	0 / 800	
DZ		@ Tj ≥ 150 °C Grade 1	48 Hrs	13, 11	3 x 000							0 / 800	0 / 800	0 / 800	0 / 800	0 / 800	0 / 800	
В3		Non-Volatile Memory Endurance, Data Retention, and Operational Life: Erase / Program Endurance @ Tj = 85 °C	according to device		1 x 77													Not applicable, because product does not include NVM.
В3	EDR	Non-Volatile Memory Endurance, Data Retention, and Operational Life: Data Retention @ Tj = 150 °C Unbiased	1000 Hrs		1 x 77													Not applicable, because product does not include NVM.

Table 5. Test group C – Package assembly integrity tests

									New stres	s test resu	lts – gener	ated on the	e product t	ype(s) to b	e qualified	i				previ generate current	c data – ously ed on the product e(s)	previously generated on other product types	
Q100 Test#	Test abbr.	Stress test conditions	Read-points	Required total # units	Lot 1	Lot 3	Lot 4	Lot 5	Lot 7	Lot 8	Lot 9	Lot 10	Lot 11	Lot 12	Lot 13	Lot 14	Lot 15	Lot 16	Lot 17	Lot 25	Lot 31	Lot 34	Comments
C1	WBS	Wire Bond Shear		30 bonds from 5 devices	Pass		Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass		See appendix for detailed test results.
			0 Hrs.	30 bonds	Pass		Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass		See appendix for detailed test results.
C2	WBP	Condition C: single bond	TC 500 cls	from 5 devices	Pass	Pass		Pass												Pass			
C3	SD	Solderability	Dry Bake	15	Pass																		See appendix for detailed test results.
C3	รบ		Steam Aging	15	Pass																		
C4	PD	Physical Dimensions		10	Pass		Pass	Pass		Pass	Pass											Pass	See dimensions report for detailed results.
C5	SBS	Solder Ball Shear		5 balls from 10 devices																			Not applicable, because device is not solder-ball surface-mount packaged (BGA).
C6	LI	Lead Integrity		10 leads from each of 5 parts																			Not applicable, because device is surface mount.
	CSAM	Scanning Acoustic Microscopy inspection		22	Pass		Pass	Pass		Pass	Pass												See appendix for detailed test results.
	Xray	Xray inspection		10	Pass		Pass		Pass	Pass		Pass		Pass		Pass		Pass					See appendix for detailed test results.

Generic

Table 6. Test group D - Die fabrication reliability tests

		ICN8		SSMC		
Q100 Test#	Failure mechanism	Sample size	Result	Sample size	Result	
D1	Electromigration	3B, 15 lines per condition	Pass	3B, 15 lines per condition	Pass	
D2	Time Dependent Dielectric Breakdown	3B x >10S	Pass	3B x >10S	Pass	
D3	Hot Carrier Injection	3B x 15S	Pass	3B x 9S	Pass	
D4	Negative Bias Temperature Instability	3B x 15S	Pass	3B x 3S	Pass	
D5	Stress Migration	> 1 cm	Pass	> 1 cm	Pass	

Table 7. Test group E - Electrical verification tests.

abic	. 1631	group E – Ele	Carlear v	GIIIIC		1 1631	· .		New stre	ee toet ra	peulte = a	enerated	on the nro	oduct type(s) to t	ne qualifie	ed.							Ger	neric dat	a – previou	sly gener	rated on t	he curren	nt product	tyne(s)					Generi	ic data =	nrevious	ly genera	ted on of	her prod	uct type	e
				I		T	1		New site	35 1651 16	esuiis – g	enerateu	on the pic	oduct type(s) to t	Je qualifie	T							Gei	lenc dat	a – previou	Siy gener	aleu oir i	The Curren	T product	lype(s)		1			Genen	T data =	previous	lly genera	Ted on or	Tier prou	uci type	1
Q100 Test#	Test abbr.	Stress test conditions	Required total # units		Lot 1	Lot 3	Lot 4	Lot 5	Lot 6	Lot 7	Lot 8	Lot 9	Lot 10	Lot 11 Lot 12	Lot 13	Lot 14	Lot 15	Lot 16	Lot 17	Lot 18 Lo	ot 19 Lot	20 Lo	t 21 Lot 2	2 Lot	23 Lot 24	Lot 25	Lot 26	Lot 27	Lot 28	Lot 29	Lot 30	Lot 31	Lot 32	Lot 33	Lot 34	Lot 35	Lot 36	Lot 37	Lot 38	Lot 39	Lot 4	0 Comments
E1		Pre- and Post-Stress Function/Parameter			Pass	Pass	Pass	Pass	s Pass	Pass	Pass	Pass	Pass	Pass Pass	Pass	Pass	Pass	Pass	Pass	Pass F	ass Pa	iss Pa	ass Pas	s Pas	ss Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	CDM (2T), No significant shifts have been observed.
E2		Electrostatic Discharge Human Body Model / Machine Model		R, H																			Pas	s Pas	ss Pass	Pass	Pass	Pass	Pass	Pass												See PPAP ESD report for detailed results.
E3	CDM	Electrostatic Discharge Charged Device Model		R, H	Pass		Pass		Pass	Pass	Pass	Pass	Pass	Pass Pass	Pass	Pass	Pass	Pass	Pass							Pass					Pass	Pass	Pass	Pass								See PPAP ESD report for detailed results.
E4	L	Latch-Up	1 x 6	R, H																																						Not applicable, because device is fabricated in latch-up immune SOI process.
E5	ED	Electrical Distributions	3 x 30	R, C, H	ı																																					See PPAP ED report for detailed results.
E6	FG	Fault Grading																																								See PPAP Certificate of Design, Construction, and Qualification (CDCC for stuck-at fault coverage. The acceptance criteria from AEC Q100-007 are met for all devices submitted for qualification.
E7	CHAR	Characterization																																								Datasheet guaranteed by wafer test and final test. See PPAP ED report for detailed results. The acceptance criteria from AEC Q003 are met.
E8	GL	Gate Leakage	1 x 6	R																																						For information only.
E9	EMC	Electromagnetic Compatibility	1 x 1																																							See PPAP EMC report for detailed results.
E10	SC	Short Circuit Characterization	3 x 10																																							Not applicable, because is not a smart power device as defined in AEC Q100 012.
E11	SER	Soft Error Rate	1 x 3																																							Not applicable, because device does not contain SRAM and is not released for ISO26262 functional safety application.

Sample sizes and acceptance criteria for Part Average Testing (PAT, AEC Q100 test #F1) are determined in accordance with AEC Q001. Sample sizes and acceptance criteria for Statistical Bin/Yield Analysis (SBA, AEC Q100 test #F2) are determined in accordance with AEC Q002.

AEC Q100 test group F on Cavity Package Integrity testing is not applicable, because the device is not assembled in a hermetic package...

Table 8. Test group Board-Level Reliability test.

			New stress test results – generated on the product type(s) to be qualified	
Test abbr.	Stress test	Required total # units	Lot 2	Comments
BL TC	Board Level Temperature Cycling -40 to +125 C on daisy-chain component	1 x 30	First fail at 3158 cls.	No completed crack in bulk of solder joint observed near both PCB and component side after 1000 and 2000 cls.

Notes:

Eta is the scale parameter in the two-parameter Weibull distribution and represents 63.2% cumulative failure rate.

2.3 Failure analysis and corrective actions

2.3.1 Cratering after WBS

Cratering was observed after wire-bond shear (WBS) testing during construction analysis of qualification lot 5. No cratering was observed after WBS testing of lots 1, 3, 7, 8, and 9. Wire-bond shear test results of lot 5 show a normal distribution, within specification, see section 3.5. An 8D investigation showed that the root cause was an abnormal ultra-sonic generator (USG) impedance. As a corrective action, the transducer of the wire-bonder was replaced, resulting in a stable USG performance. Furthermore, a system based on an out-of-control plan (OCAP) was built to monitor the USG performance and to replace the transducer. Also, the spec to check cratering during ball-shear test after wire-bonding was updated. Additionally, actions were taken to prevent reoccurrence, such as updating the FMEA. The first 10 assembled production lots were checked for cratering during ball-shear test, applying a sample size of 5 units per lot. No cratering was observed.

2.3.2 Lead delamination after PCON

After pre-conditioning before HAST of lot 5, CSAM analysis showed lead delamination on 2 samples out of 14, see Table 3. No delamination was observed on lots 1 and 3. Also, no delamination was found after PCON for lot 5 samples for TC. Visual inspection showed plating peel-off on the leads. During an 8D investigation, the lead delamination was not observed on other samples, even not after PreCon was performed on 77 samples of both the affected lot and a control lot. Checks of the process mapping and process variation did not show any abnormalities. The plating peel-off was discussed with the lead-frame supplier, but that did not reveal any abnormalities or give an indication of the root cause. Also other investigations did not reveal a potential root cause. As corrective actions, the following measures have been defined:

- The sample size for the plating peel-off test at incoming inspection was increased for the first 20 batches. No plating peel-off was observed.
- 100% automated optical inspection (AOI) was installed for the first 10 assembled production lots. No abnormalities were observed.
- CSAM analysis was performed for the first 10 assembled production lots, to check for lead delamination. No delamination was observed.
- PCON followed by CSAM analysis was performed for the first 10 assembled production lots. No delamination was observed, neither at 0 hrs nor after PCON.

The results from these measures all passed the criteria. Therefore, the lead delamination, observed on only two devices during qualification, was a one-time incident.

2.4 Conclusions

TJA1028TK, TJA1042TK/3, TJA1049TK, TJA1049TK/3, and TJA1051TK/3 in HVSON8 (SOT782-1), manufactured in ICN8 or in SSMC wafer-fab and assembled in ATBK or ASEN, with 18- μ m Au-wire, can be released for mass production. The qualification results comply with NXP's internal requirements and AEC-Q100 Rev G, Grade 1 [1].

2.5 References

- 1. Failure mechanism based stress test qualification for integrated circuits, AEC-Q100 Rev-G, May 17, 2007.
- 2. Pb-free test requirements, AEC Q005 Rev-A, June 1, 2010.
- 3. Dimensional Results (part of PPAP).
- 4. ESD Report (part of PPAP).
- 5. Electrical Distribution Report (part of PPAP).
- 6. EMC Test Report (part of PPAP).
- 7. Joint Industry Standard Moisture/Reflow Sensitivity Classification for Nonhermetic Surface Mount Devices, IPC/JEDEC J-STD-020E, December 2014.

3. Appendices

3.1 Product info

#	Item	Description
1	Customer part number	
2	Supplier part number and data sheet	TJA1028TK/5V0/10, TJA1028TK/5V0/20, TJA1042TK/3, TJA1049TK, TJA1049TK/3, TJA1051TK/3
3	Device Description	TJA1028TK: LIN transceiver, combined with a low-drop, on-board voltage regulator.
		TJA1042TK/3, TJA1051TK/3: third generation high-speed CAN transceivers, providing an interface between CAN protocol controller and physical two-wire CAN bus; variant for direct interfacing to microcontrollers with supply voltages from 3 to 5 V.
		TJA1049TK: third generation high-speed CAN transceiver, providing an interface between CAN protocol controller and physical two-wire CAN bus.
		TJA1049TK/3: variant of TJA1049TK for direct interfacing to microcontrollers with supply voltages from 3 to 5 V.
4	Wafer / Die Fab Location & Process ID: a. Facility name / plant #: b. Street address: c. Country: d. Process ID:	SSMC 70 Pasir Ris Industrial Drive 1 Singapore ZM34_PA100TMX04
	e. Facility name / plant #: f. Street address: g. Country: h. Process ID:	ICN8 Gerstweg 2, 6534AE Nijmegen The Netherlands PA100TMX04
5	Wafer Probe Location: a. Facility name / plant #: b. Street address: c. Country:	NXP Manufacturing Thailand / ATBK 303 Moo 3 Chaengwattana Rd Laksi, Bangkok 10210 Thailand
6	Assembly Location & Process ID: a. Facility name / plant #: b. Street address: c. Country: d. Process ID:	NXP Manufacturing Thailand / ATBK 303 Moo 3 Chaengwattana Rd Laksi, Bangkok 10210 Thailand HVSON8 (SOT782-1)
	e. Facility name / plant #: f. Street address: g. Country: h. Process ID:	ASEN (current name: ATX-SZ) 188 Su Hong Xi Road, Suzhou Industrial Park, Suzhou China HVSON8 (SOT782-1)
7	Final Quality Control A (Test) Location: a. Facility name / plant #: b. Street address:	NXP Manufacturing Thailand / ATBK 303 Moo 3 Chaengwattana Rd Laksi, Bangkok 10210

	o Country	Theiland
	c. Country:	Thailand
	a. Facility name / plant #:	ASEN (current name: ATX-SZ)
	b. Street address:	188 Su Hong Xi Road, Suzhou Industrial Park, Suzhou
	c. Country:	China
8	Wafer / Die:	
	a. Wafer size:	200mm
	b. Die family:	TJA1028TK: LIN transceiver
		TJA1042TK/3: CAN transceiver
		TJA1049TK(/3): CAN transceiver TJA1051TK/3: CAN transceiver
	c. Die mask set revision & name:	TJA1031TK/3. CAN transceiver TJA1028TK: tf1433A (SSMC) / cf1433A (ICN8)
	C. Die mask set revision & name.	TJA1042TK/3: tf1361D (SSMC) / cf1361D (ICN8)
		TJA1049TK(/3): tf1521A (SSMC) / cf1521A (ICN8)
		TJA1051TK/3: tf1371C (SSMC) / cf1371C (ICN8)
	d: Die photo	See the PPAP's Certificate of Design, Construction, and
		Qualification (CDCQ)
9	Wafer / Die Technology Description:	
	a. Wafer / Die process technology:	A-BCD3
	b. Die channel length:	1 µm
	c. Die gate length: d. Die supplier process ID (Mask #):	1 µm ZM34_PA100TMX04 (SSMC) / PA100TMX04 (ICN8)
	e. Number of transistors or gates:	ZIVISA_I ATOUTIVIAUA (OSIVIC)/T ATOUTIVIAUA (ICINO)
	f. Number of mask steps	19
10	Die Dimensions (excluding saw lane):	
1	a. Die width:	TJA1028TK: 1.51 mm
		TJA1042TK/3: 1.41 mm
		TJA1049TK(/3): 1.41 mm
	h Dio longth:	TJA1051TK/3: 1.40 mm TJA1028TK: 2.16 mm
	b. Die length:	TJA1028TK: 2.16 mm TJA1042TK/3: 1.99 mm
		TJA1049TK(/3): 1.99 mm
		TJA1051TK/3: 1.84 mm
L	c. Die height:	280 μm
11	Die Metallization:	
	a. Die metallization material(s):	TiTiN / AlCu (0.5%)/ TiN
	b. Number of layers:	3
	c. Thickness (per layer):	M1: 600nm; M2: 600nm; M3: 900nm
4.5	d. % of alloys (if present):	
12	Die Passivation:	
	a. Number of passivation layers b. Die passivation material(s):	3 HDP Oxide / SRO / Silicon nitride
	c. Thickness(es):	1.75 µm
13	Die Overcoat Material:	Wafer coating (Polyimide) 4 µm
L	2.2 Overesat Material.	The state of the s
14	Die cross-section of the basic structure	See Appendix A of the PPAP's Certificate of Design,
		Construction, and Qualification (CDCQ)
15	Die Prep Backside:	
	a. Die prep method:	Chemical etched
	b. Die metallization:	None
	c. Thickness(es):	n.a.

16	Die Separation Method:	
	a. Kerf width (μm)	
	b. Kerf depth (if not 100% saw):	n.a.
	c. Saw method:	Sawing
17		3
17	Die Attach:	014540
	a. Die attach material ID:	QMI519
	b. Die attach method:	Glue
	c. Die placement diagram:	See Appendix B of the PPAP's Certificate of Design,
		Construction, and Qualification (CDCQ)
18	Package:	, ,
'	a. Type of package:	Surface Mount Device
	b. Ball / lead count:	8 Pins
	c. JEDEC designation:	MO-229
	d. Lead (Pb) free:	Yes
	e. Package outline drawing:	cf. datasheet
19	Mold Compound:	
	A Mold compound supplier ID:	Hitachi
	b. Mold compound type:	CEL-9220
	c. Flammability rating:	UL-94-VO-1/8
	d. Fire retardant type / composition:	OL-34-VO-1/0
		400
	e. Tg (glass transition temperature) (°C):	120
	f. CTE (above & below Tg) (ppm/°C):	CTE1 (below Tg) = 8, CTE2 (above Tg) = 33
20	Wire Bond:	
	a. Wire bond material:	AuPd
	b. Wire bond diameter:	18 µm
	c. Type of wire bond at die:	Ball bond
	d. Type of wire bond at leadframe:	Stitch bond
	e. Wire bonding diagram:	See Appendix B of the PPAP's Certificate of Design,
		Construction, and Qualification (CDCQ)
21	Lead frame	
	a. Paddle / flag material:	CuFe2P
	b. Paddle / flag width:	1.94 mm (TJA1028TK) / 1.90 [TJA1042TK/3,
	·-· · ·· · · · · · · · · · · · · ·	TJA1049TK(/3), TJA1051TK/3]
	c. Paddle / flag length:	2.70 mm (TJA1028TK) / 2.50 [TJA1042TK/3,
	s. r addio / hag longth.	TJA1049TK(/3), TJA1051TK/3]
	d Paddle / flag plating composition:	NiPdAuAg, roughened
	d. Paddle / flag plating composition:	
	e. Paddle / flag plating thickness:	Ni 0.5 μm, Pd 0.005 μm, Au 0.005 μm, Ag 0.005 μm
	f. Leadframe material:	CuFe2P
	g. Leadframe bonding plating	NiPdAuAg
	composition:	
	h. Leadframe bonding plating thickness:	Ni 0.5 μm, Pd 0.005 μm, Au 0.005 μm, Ag 0.005 μm
	i. External lead plating composition:	NiPdAuAg
	j. External lead plating thickness:	Ni 0.5 μm, Pd 0.005 μm, Au 0.005 μm, Ag 0.005 μm
22	Substrate: (if applicable):	Not applicable
		ι τοι αργιιοαρίο
	a. Substrate material (e.g., FR5, BT, etc.):	
	b. Substrate thickness (mm):	
	c. Number of substrate metal layers:	
	d. Plating composition of ball solderable	
	surface:	
	e. Panel singulation method:	
	f. Solder ball composition:	
	g. Solder ball diameter (mm):	
	J 51451 5411 414110tor (11111).	I .

23	Unpackaged Die:	Not applicable
24	Header Material:	Not applicable
25	Derived value of $\theta_{\text{JA:}}$	50 K/W (in free air, 2S2P board)
26	Test circuits, bias levels & operational conditions imposed during the supplier's life and environmental tests:	See appendices C and D of the PPAP's Certificate of Design, Construction, and Qualification (CDCQ)
27	Fault Grade Coverage:	>99 %
28	Maximum Process Exposure Conditions	SnPb: MSL1 @ 240°C (max dwell time:20 s) Pb free: MSL1 @ 260°C (max dwell time:30 s)

3.2 Application mission profile

The mission profile listed in Table 9 has been used to assess suitability of the product types for their intended application. This mission profile is the collection of relevant environmental and functional loads that the product types will be exposed to during their lifetime.

Table 9. Mission Profile

able 3. W	ISSION Profile	U			<u> </u>			
ľ	Mission	Profile	'Automo	otive' (c	overing AE	C Q100 gı	rade	1)
			Operation			Field Lifetime =	15	Years
Field	Power-On-	Hours (POH)	Relevant Tem	neratures	Stimuli	Power On Hours =	2.2	hours/day
Lifetime		. ,	Troiovant Ton	.porataroo	- Ctimum	cycles/day =	2	cycles/day
years	hours/day	hours/field life	$T_{j,max-eff}$	Ta	(V, I, f, loading)	T _{a,max-eff} =	84 °C	
15 years	2.2 h	12000 h	109 °C	-40 to 125 °C	Application Specific	$\Delta T_{\text{self}} =$	25 °C	
		Thermo	Mechanical Load	ding		$T_{j,max-eff} =$	109 °C	
Field Lifetime	Power	Cycles	Relevant Ten	nperatures	Effective Temperature Cycle	T _a =	-40 to 125	°C
years	cycles/day	cycles/field life	$T_{j,max-eff}$	$T_{e,min-eff}$	ΔT _{eff}	T _{e,min-eff} = (TC / BL TC)	-3 °C	4 °C
15 years	2 c	10950 с	109 °C	-3 °C	112 °C	$T_{trop,day} =$	30 °C	
		Hu	mid Environment	•		T _{trop,night} =	15 °C	
Field Lifetime	Time Standl	by (with bias)	Relevant Tem	nperatures	Relative Humidity	Relative humidity =	95%	
years	hours/day	hours/field life	$T_{trop,day}$	T _{trop,night}		T _{solderjoint,max-eff} =	109 °C	
15 years	21.8 h	119400 h	30 °C	15 °C	95%			
		Н	ot Environment					
Field Lifetime		ne Standby ne Off	Relevant Tem	nperatures				
years	hours/day	hours/field life	$T_{j,max-eff}$	T _{trop,day}				
15 years	2.2 + 21.8 + 0 h	131400 h	109 °C	30 °C				

Based on the mission profile, the stress test read points for the relevant reliability tests have been defined, see Table 10.

Table 10. Stress test conditions and read-points.

Test	Conc	dition	Based on mission profile	Standard read point	Robust read point
HTOL	150 °C		1519 h	1000 h	2000 h
HTSL	175 °C		223 h	500 h	1000 h
TC	-65 °C	150 °C	798 c	500 c	1000 c
THB	85 °C	85%	1640 h	1000 h	2000 h
BL TC	-40 °C	125 °C	4256 c	1500 c	3500 с

3.3 Qualification by similarity

Tables 11 - 15 show the relevant product parameters that were considered in the qualification by similarity assessment for MSLA, TC, HAST, HTSL, and BL-TC, respectively. The cells with yellow fill color indicate the parameters that were key in selecting the lead vehicles.

Table 11. MSLA structural similarity

	More critical if	Product to be qualified	Product to be qualified	Product to be qualified	Product to be qualified
Product type name/version		TJA1028TK	TJA1042TK/3	TJA1049TK(/3)	TJA1051TK/3
Die size in mm	N/A	2.16 x 1.51	1.99 x 1.41	1.99 x 1.41	1.84 x 1.40
Bady size in nam	Larray	3 x 3 x 0.85	3 x 3 x 0.85	3 x 3 x 0.85	3 x 3 x 0.85
Body size in mm	Larger	SOT782-1	SOT782-1	SOT782-1	SOT782-1
Tpeak Reflow	Higher	260C	260C	260C	260C
Total body thickness in mm	Larger	0.85	0.85	0.85	0.85
Thickness MC die top to body top	Larger	0.37	0.37	0.37	0.37
Asymmetry of package	Lawren	avenaged dia ward	averaged dia ward	averaged dia ward	averaged dia ward
MC thickness under die pad in mm	Larger	exposed die pad	exposed die pad	exposed die pad	exposed die pad
Die pad size in mm (diagonal)	Larger, as long as die/die-pad	3.32	3.14	3.14	3.14
Die - die pad ratio in % (diagonal)	ratio is the same within 15%	81%	80%	80%	76%
Length of lead within package in mm	Larger	0.4	0.4	0.4	0.4
Wire length (in µm)	Smaller	758 max	989 max	989 max	989 max
Wire length embedded in Chipcoat	Shorter	N.A.	N.A.	N.A.	N.A.
Die free surface area (for stacked dies)	Larger	N.A.	N.A.	N.A.	N.A.

Table 12. TC structural similarity

	More critical if	Product to be qualified	Product to be qualified	Product to be qualified	Product to be qualified
Product type name/version		TJA1028TK	TJA1042TK/3	TJA1049TK(/3)	TJA1051TK/3
die size in mm	N/A	2.16 x 1.51	1.99 x 1.41	1.99 x 1.41	1.84 x 1.40
Damage response after MSLA	Worse	Equal	Equal	Equal	Equal
Total body thickness in mm	Larger	0.85	0.85	0.85	0.85
Thickness MC die top to body top	Larger	0.37	0.37	0.37	0.37
Asymmetry of the subpackage MC below the die pad	Larger	N.A.	N.A.	N.A.	N.A.
Die pad size in mm (diagonal) Die - die pad ratio in % (diagonal)	Larger as long as die/die-pad ratio is the same within 15%	3.32 81%	3.14 80%	3.14 80%	3.14 76%
Wire length (in µm)	shall be equal or smaller	758 max	989 max	989 max	989 max
Wire diameter	shall be equal or smaller	18 µm	18 µm	18 µm	18 µm
Solder Ball diameter	shall be equal or smaller	N.A.	N.A.	N.A.	N.A.
Wire length embedded in Chipcoat	shall be equal or shorter	N.A.	N.A.	N.A.	N.A.
Overhang of the top die	shall be equal or larger	N.A.	N.A.	N.A.	N.A.

Table 13. HAST structural similarity

	More critical if		uct to be alified	Product to be qualified	Product to be qualified	Product to be qualified	Product to be qualified
Product type name/version		TJA	1028TK	TJA1042TK/3	TJA1049TK	TJA1049TK/3	TJA1051TK/3
Damage response after MSLA	Worse	E	qual	Equal	Equal	Equal	Equal
Thickness MC die top to body top	Smaller	().37	0.37	0.37	0.37	0.37
Applied E-field Between any metal parts if pass data extends to 2x the required readpoint, the applied E-field of the reference can be 50% smaller.	l		0.15mm V/mm	5V / 0.15mm 33 V/mm			

Table 14. HTSL structural similarity

	More critical if	Product to be qualified	Product to be qualified	Product to be qualified	Product to be qualified	Product to be qualified
Product type name/version		TJA1028TK	TJA1042TK/3	TJA1049TK	TJA1049TK/3	TJA1051TK/3
Wire diameter	Smaller	18 μm	18 μm	18 μm	18 μm	18 μm

Table 15. BL-TC structural similarity

	More critical if	Product to be qualified			
Product type name/version		TJA1028TK	TJA1042TK/3	TJA1049TK(/3)	TJA1051TK/3
Body size in mm	Larger	3.0 x 3.0	3.0 x 3.0	3.0 x 3.0	3.0 x 3.0
Solder volume	Smaller	equal	equal	equal	equal
Pitch in mm	Not equal	0.65	0.65	0.65	0.65
Die size in mm	Larger	2.16 x 1.51	1.99 x 1.41	1.99 x 1.41	1.84 x 1.40
Array size / pin count	Larger	8	8	8	8

3.4 Final test at read-points

The final-test temperatures applied at the various read-points of the reliability and electrical robustness tests are listed in Table 16.

Table 16. Final-test temperatures at read points³

Test	Abbr.	Cold (-40 °C)	Room (25 °C)	Hot (125 °C)3
Electrical Distribution	ED	Х	Х	Х
ESD Human Body Model	НВМ		Χ	Χ
ESD Charged Device Model	CDM		Χ	Χ
Early Life Failure Rate	ELFR		Х	Х
High Temperature Operating Life	HTOL	Χ	Χ	Χ
High Temperature Storage Life	HTSL		Χ	Χ
Highly Accelerated Stress Test	HAST	Х	Х	Х
Temperature Cycling	TC	Х	Х	Х

Parameter shift analyses were performed after HTOL, HBM, and CDM (up to spec level and one level above).

 $^{^{\}rm 3}$ Table also covers final testing after preconditioning prior to HAST and TC tests.

3.5 Wire bond shear

The 0-hrs wire ball shear results are shown in Table 17.

Table 17. 0-hrs Wire bond shear results (post seal)

	QB1	QB3	QB4	QB5	QB6	QB7	QB8	QB9	QB10	QB11	QB12	QB13	QB14	QB15		
Parameter	New stress test results – generated on the product type(s) to be qualified									Generic data – previously generated on the current product type(s)						
Qual Lot ID	Lot 1	Lot 4	Lot 5	Lot 7	Lot 8	Lot 9	Lot 10	Lot 11	Lot 12	Lot 13	Lot 14	Lot 15	Lot 16	Lot 17	Lot 25	Lot 23
Ball Shear Average [g]	26.65	25.73	27.10	26.93	24.28	23.79	24.94	25.39	24.65	25.44	24.57	26.20	25.18	24.51	39.26	25.85
Highest Reading [g]	29.26	34.36	28.93	28.54	27.08	25.34	28.61	27.94	28.11	27.12	27.43	28.02	27.93	28.02	42.71	29.19
Lowest Reading [g]	24.71	22.73	23.68	25.67	22.81	21.79	22.98	23.32	21.63	23.25	20.34	23.72	22.01	21.44	35.21	21.88
Standard deviation	0.92	1.96	0.99	0.66	0.86	0.83	1.09	0.99	1.28	0.98	1.45	0.86	1.38	1.45	1.7	1.71
Sample size [#wires from #samples]	50 wires from 5 samples	55 wires from 5 samples	50 wires from 5 samples	55 wires from 5 samples	50 wires from 5 samples	50 wires from 5 samples	55 wires from 5 samples	60 wires from 5 samples	55 wires from 5 samples	60 wires from 5 samples	55 wires from 5 samples	60 wires from 5 samples	55 wires from 5 samples	60 wires from 5 samples	50 wires from 5 samples	55 wires from 5 samples
Failure Mode:	-				-											
Bond Shear / Al Shear	98%	100%	86%	100%	100%	94%	100%	93%	100%	100%	43%	92%	55%	15%	100%	62%
Metal Peel Off	2%	0%	8%	0%	0%	6%	0%	7%	0%	0%	57%	8%	46%	85%	0%	27%
Cratering/COUB	0%	0%	6%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0	0
Avg. Ball Bond diameter in µm	50	53	47	53	50	52	49	50	50	48	51	49	50	50	61	
AEC-Q100 specified Minimum Sample Average [g]	18	20	21	20	18	20	16	18	18	16	18	16	18	18	18.8	12
AEC-Q100 Minimum individual Shear Reading [g]	12	14	10	14	12	14	11	12	12	11	12	11	12	12	10.9	
Ppk (>1.67)	5.31	1.99	5.76	6.52	4.77	3.95	4.26	4.51	3.29	4.91	2.89	5.89	3.18	2.88	5.57	2.7
Conclusion against AEC-Q100 requirements	Pass	Pass	Fail *	Pass	Pass	Pass	Pass	Pass	Pass	Pass						

a. Cratering was observed as failure mode during ball-shear test. This problem has been addressed and resolved, see section 2.3.

3.6 Wire bond pull 0 hrs

The 0-hrs wire bond pull results are shown in Table 18.

Table 18. 0-hrs Wire bond pull results (post seal)

	QB1	QB3	QB4	QB5	QB6	QB7	QB8	QB9	QB10	QB11	QB12	QB13	QB14	QB15		
Parameter	New stress test results – generated on the product type(s) to be qualified								Generic data – previously generated on the current product type(s)							
Qual Lot ID	Lot 1	Lot 4	Lot 5	Lot 7	Lot 8	Lot 9	Lot 10	Lot 11	Lot 12	Lot 13	Lot 14	Lot 15	Lot 16	Lot 17	Lot 25	Lot 23
Bond Pull Average [g]	6.88	6.73	7.29	7.39	7.70	7.11	7.66	7.57	7.77	7.39	7.81	7.58	7.68	7.62	9.3	7.47
Highest Reading [g]	7.87	8.36	8.29	9.04	8.97	7.59	9.40	9.54	9.54	9.04	8.70	8.39	8.57	8.54	10.09	8.83
Lowest Reading [g]	5.43	4.08	6.60	5.23	6.49	6.64	5.00	6.10	6.29	5.23	6.81	6.36	6.35	6.10	8.46	5.54
Standard deviation	0.53	0.87	0.38	0.96	0.53	0.22	0.84	0.79	0.70	0.96	0.47	0.49	0.45	0.56	0.36	0.83
Sample size [#wires from #samples]	50 wires from 5 samples	55 wires from 5 samples	50 wires from 5 samples	55 wires from 5 samples	50 wires from 5 samples	50 wires from 5 samples	55 wires from 5 samples	60 wires from 5 samples	55 wires from 5 samples	60 wires from 5 samples	55 wires from 5 samples	60 wires from 5 samples	55 wires from 5 samples	60 wires from 5 samples	50 wires from 5 samples	55 wires from 5 samples
Failure Mode:	samples	samples	samples	samples	samples	samples	samples	samples	samples	samples	samples	samples	samples	samples	samples	samples
Break on intermetallic	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
Ballneck break	100%	100%	100%	100%	100%	100%	100%	100%	100%	100%	100%	100%	100%	100%	100%	100%
Wire fracture	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
AEC-Q100 specified Minimum [g]	pecified Minimum [g] ≥ 2.0									•						
Ppk (>1.67)	3.05	1.82	4.68	1.87	3.56	7.63	2.25	2.35	2.75	1.87	4.12	3.80	4.21	3.35	7.02	2.1
Conclusion against AEC-Q100 requirements	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass	Pass

3.7 Wire bond pull after TC 500 cls

The wire bond pull results after TC 500 cycles are shown in Table 19.

Table 19. TC 500-cls Wire bond pull results (post seal)

Parameter	New stress to produc	Generic data – previously generated on the current product type(s)		
Qual Lot ID	Lot 1	Lot 3	Lot 5	Lot 17
Bond Pull Average [g]	7.17	7.33	7.42	9.34
Highest Reading [g]	8.83	8.31	8.87	10.73
Lowest Reading [g]	5.27	6.62	6.22	8.69
Standard deviation	0.65	0.45	0.59	0.47
Sample size [#wires from #samples]	50 wires from 5 samples	50 wires from 5 samples	50 wires from 5 samples	50 wires from 5 samples
Failure Mode:	·			
Break on intermetallic	0%	0%	0%	0
Ballneck break	100%	100%	100%	1
Wire fracture	0%	0%	0%	0
AEC-Q100 specified Minimum [g]		2.0		
Ppk (>1.67)	2.65	3.97	3.05	5.32
Conclusion against AEC-Q100 requirements	Pass	Pass	Pass	Pass

3.8 Solderability

The solderability results for are shown in Table 20. The solder reflow is defined according to the guidelines for Pb-free assembly in IPC/JEDEC J-STD-020E [7].

Table 20. Solderability results

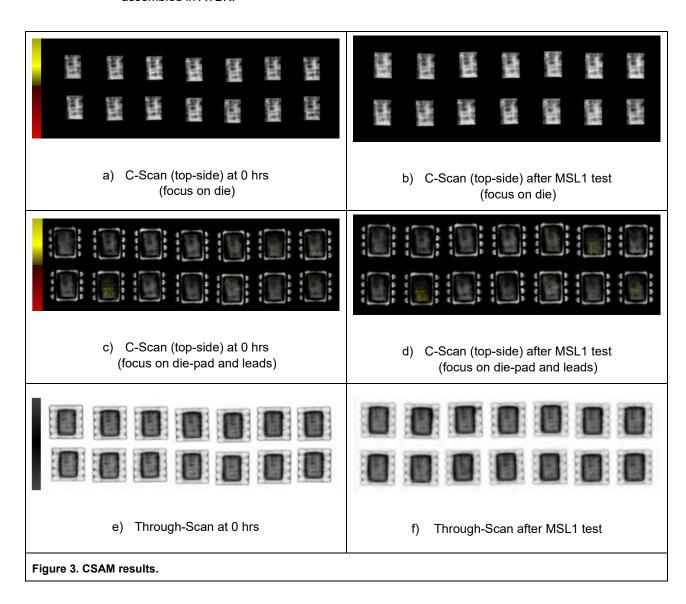
Parameter	New stress test results – generated on the product type(s) to be qualified
Qual Lot ID	Lot 1
Method	SMT
Profile	NXP
Precondition	Steam aging 1 hour
SnPb Profile	15 / 15
Pb-Free Profile	15 / 15
Precondition	Dry bake 150 °C 16 hours
SnPb Profile	15 / 15
Pb-Free Profile	15 / 15
Visual Inspection	
Solder Defects	None
Solder Coverage	Acceptable

3.9 Solder ball shear

Solder ball shear testing is not applicable, because the device's package does not include solder balls.

3.10 CSAM

The images shown in Figure 3 show the CSAM results of lot 1 that have been collected during moisture sensitivity level assessment (MSLA). No delamination was observed, neither at 0 hrs nor after MSL1 test. The images refer to lot 1 manufactured in SSMC and assembled in ASEN, but are also representative for other analyzed lots, including those manufactured in ICN8 and/or assembled in ATBK.



After PCON of lot 5, lead delamination was observed, see Figure 4. This issue is discussed in section 2.3.2.

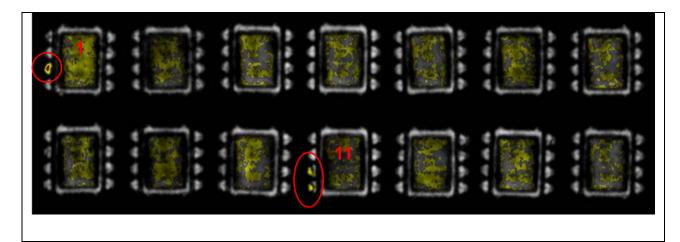


Figure 4. Lead delamination observed after PCON before HAST for lot 5.

3.11 XRAY

Figure 5 shows an X-ray image of a qualification sample, illustrating lead-frame design, internal package structure, and wiring. The images refer to lot 1 manufactured in SSMC and assembled in ASEN, but are also representative for other analyzed lots, including those manufactured in ICN8 and/or assembled in ATBK.

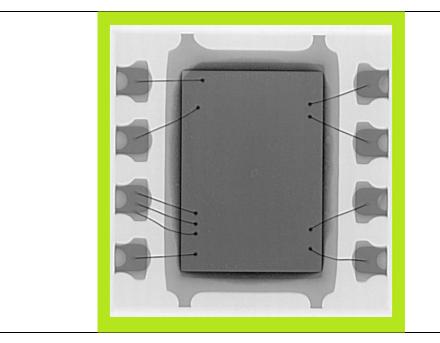


Figure 5. X-ray photo.

3.12 Wire-diameter change (20 to 18 μm) at ATBK

With the quadruple-source release, a wire-diameter change from 20 to 18 μm is introduced for TJA1028TK, TJA1042TK/3, and TJA1051TK/3 in HVSON8 (SOT782-1) at ATBK. The risk of the wire diameter change is very low, because multiple other product types from PL IVN (TJA1044TK, TJA1044TK/3, TJA1057TK, TJA1057TK/3) manufactured in wafer fabs ICN8 and SSMC have already been released with 18- μm wire diameter at ATBK and are running in volume production.

TJA1028TK, TJA1042TK/3, and TJA1051TK/3 with 20- μ m wire diameter are fully structural similar to the same product type assembled with 18- μ m wire diameter for accelerated environment stress tests (test group A). The 0-hrs performance specifically related to the wire-diameter change and, therefore, to the wire-bonding process have been experimentally verified, for dies manufactured both in ICN8 and in SSMC wafer fabrication sites. The construction analysis results are listed in Table 5.

Additionally, CDM testing was performed, for both ICN8 and SSMC dies. The CDM results are listed in Table 7.